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	Application No.	Applicant(s)
Notice of Allowability	09/551,233	MATSUURA ET AL.
	Examiner	Art Unit
	Hsien-ming Lee	2823
The MAILING DATE of this communication appeal of the communication appeal claims being allowable, PROSECUTION ON THE MERITS IS therewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT ROOF the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in or other appropriate commu IGHTS. This application is s	n this application. If not included unication will be mailed in due course. <b>THIS</b>
1. $\boxtimes$ This communication is responsive to <u>5/25/2005</u> .		•
2. X The allowed claim(s) is/are 12.		
3. The drawings filed on are accepted by the Examiner.		
4. Acknowledgment is made of a claim for foreign priority up a) All b) Some* c) None of the:  1. Certified copies of the priority documents have 2. Certified copies of the priority documents have 3. Copies of the certified copies of the priority documents have International Bureau (PCT Rule 17.2(a)).  * Certified copies not received:  Applicant has THREE MONTHS FROM THE "MAILING DATE" noted below. Failure to timely comply will result in ABANDONN THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.	e been received. e been received in Application cuments have been received of this communication to file	on No  d in this national stage application from the
5. A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.		
<ol> <li>CORRECTED DRAWINGS (as "replacement sheets") mu         <ul> <li>(a) ☐ including changes required by the Notice of Draftspers</li> <li>1) ☐ hereto or 2) ☐ to Paper No./Mail Date</li> <li>(b) ☒ including changes required by the attached Examiner</li> <li>Paper No./Mail Date 5.</li> </ul> </li> </ol>	son's Patent Drawing Reviev	
Identifying indicia such as the application number (see 37 CFR 1 each sheet. Replacement sheet(s) should be labeled as such in	I.84(c)) should be written on to the header according to 37 CF	he drawings in the front (not the back) of FR 1.121(d).
DEPOSIT OF and/or INFORMATION about the depo attached Examiner's comment regarding REQUIREMENT	OSIT OF BIOLOGICAL MATE FOR THE DEPOSIT OF BIO	ERIAL must be submitted. Note the DLOGICAL MATERIAL.
Attachment(s) 1.  Notice of References Cited (PTO-892)		formal Patent Application (PTO-152)
2. X Notice of Draftperson's Patent Drawing Review (PTO-948)		ummary (PTO-413), /Mail Date
3. Information Disclosure Statements (PTO-1449 or PTO/SB/Paper No./Mail Date	08), 7. ☐ Examiner's	Amendment/Comment
4. Examiner's Comment Regarding Requirement for Deposit		Statement of Reasons for Allowance
of Biological Material	9. 🗌 Other	HSIENLAING LEE
		PRIMARY EXAMINER
		Statement of Reasons for Allowance   HSIEN-MING LEE PRIMARY EXAMINED  5/3//2005

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## **DETAILED ACTION**

## Remarks

1. Applicants' cancellation to claims 1-11 and 13-28 is acknowledged. Claim 12 is pending in the application.

2. Applicants are required to submit corrected drawings as the drawings, which were submitted on 4/17/2000, have been objected by the examiner as set forth in the Office action of Paper No. 5. Also see the notice of draftsperson's patent drawing review.

## Allowable Subject Matter

- 3. Claim 12 is allowed.
- 4. The following is an examiner's statement of reasons for allowance:

The closest prior art of record, Cuchiaro et al. (US 6, 165,802), teach a method of fabricating a semiconductor device having a ferroelectric capacitor 118, as stated previously.

In contrast, Cuchiaro et al. do not teach crystallizing the ferroelectric film under a reduced total pressure in the range between l Torr and 40 Torr such that peeling of the ferroelectric film is substantially reduced.

Chu et al. to US 6,287,637 teach crystallizing the PZT ferroelectric film under a reduced oxygen partial pressure atmosphere (col. 6, lines 41-47) in the range of 10 <sup>-4</sup> to 100 Torr, wherein the reduced oxygen pressure is a partial not a total pressure. Although Chu et al. suggest that crystallizing the ferroelectric film can be performed in a pure oxygen ambient, Chu et al. however, do not teach that the reduced total pressure of oxygen is in the range between 1 Torr and 40 Torr.

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In the examiner's opinion, it would not have been obvious to one of the ordinary skill in the art, at the time of the invention was made, to modify the teachings of Cuchiaro et al. with the teachings of Chu et al.

5. Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Hsien-ming Lee whose telephone number is 571-272-1863. The examiner can normally be reached on Tuesday-Thursday ( $8:00 \sim 6:00$ ).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Olik Chaudhuri can be reached on 571-272-1855. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Hsien-ming Lee Primary Examiner Art Unit 2823

PRIMARY EXAMINED S/31/2005

May 31, 2005